

SEMI Standards Staff Report

October 18, 2016 v1.3

SEMI Japan

SEMI Global 2016 Calendar of Events [1/2]

Event Name	Event Details
SEMICON Europa 2016	October 25-27, 2016 Grenoble, France
International Technology Partners Conference (ITPC) 2016	October 30-November 2, 2016 Maui, Hawaii
SEMICON Japan 2016	December 14-16, 2016 Tokyo, Japan
SEMICON Korea 2017	February 8-10, 2017 Seoul, South Korea
FPD China 2017	March 14-16, 2017 Shanghai, China
SEMICON China 2017	March 14-16, 2017 Shanghai, China

SEMI Global 2016 Calendar of Events [2/2]

Event Name	Event Details
LED Taiwan 2017	April 12-15, 2017 Taipei, Taiwan
SEMICON Southeast Asia 2017	April 25-27, 2017 Penang, Malaysia
Intersolar Europe	May 31-June 2, 2017 Munich, Germany
Intersolar North America	July 11-13, 2017 San Francisco, CA
SEMICON West 2017	July 11-13, 2017 San Francisco, CA
SEMICON Taiwan 2017	September 13-15, 2017 Taipei, Taiwan
PV Taiwan 2017	September 18-20, 2017 Taipei, Taiwan

2016 SEMI Standards Excellence Award

- Terry Asakawa/Tokyo Electron
 - envisioned how the SEMI Standards Program could effectively address simpler, flow-oriented manufacturing in industries outside of semiconductor manufacturing.
 - active in development work to enhance the GEM300 Standards with contemporary concepts such as schemes for secure recipe management and use of prediction in real time carrier logistics controls.
 - continues to make major contributions to increasing the usability and relevance of SEMI equipment communication Standards, which are essential to Smart Manufacturing.



Global Standards Meeting Schedule

<http://www.semi.org/en/standards-events>

- OCT 18, 2016
Assembly & Packaging Japan TC Chapter Meeting
Tokyo, Japan
- OCT 21, 2016
Information & Control Japan TC Chapter Meeting
Tokyo, Japan
- OCT 25-26, 2016
SEMICON Europa Standards Meetings
Grenoble, France
<http://www.semiconeuropa.org/node/3426>
- NOV 7-10, 2016
North America Standards Fall Meetings
San Jose, California
<http://www.semi.org/en/node/84311>
- NOV 9, 2016
FPD Materials & Components / FPD Metrology Japan TC
Chapter Meeting
Tokyo, Japan
- NOV 25, 2016
Photovoltaic China TC Chapter Meeting
Changshu, China
- DEC 13-16, 2016
SEMICON Japan Standards Meetings
Tokyo, Japan
- JAN 27, 2017
3DS-IC Japan TC Chapter Meeting
Tokyo, Japan
- FEB 9, 2017
SEMICON Korea Standards Meetings
Seoul, South Korea

SEMICON Europa

Date	Program	Time	Location
TUESDAY 25 Oct 2016	Automation Technology (TC) CANCELED	10:00–13:00	Room: Bayard
	Gases & Liquid Chemicals (TF)	14:00–17:00	Room: Bayard
	Int'l Polished Wafer (TF)	11:00–12:00	Room: Diguieres
	Silicon Wafer GCS (By Invitation Only)	12:00–13:00	Room: Diguieres
	Int'l Advanced Surface Inspection (TF)	14:00–15:00	Room: Diguieres
	Int'l Advanced Wafer Geometry (TF)	15:00–17:00	Room: Diguieres
WEDNESDAY 26 Oct 2016	Gases & Liquid Chemicals (TC)	10:00–13:00	Room: Bayard
	Silicon Wafer (TC)	14:00–16:00	Room: Bayard
	ERSC (By Invitation Only)	16:30–18:00	Room: Bayard
	Metrics/PIC/IC (TF & TC)	14:00–16:00	Room: Diguieres

North America Standards Fall 2016

- Draft Schedule Last Updated: October 13, 2016



NA Fall 2016
Schedule

SEMICON Japan Standards Meetings 2016

- Draft Schedule Last Updated: September 9






2016_STD会議棟
割当_20160909

2016 Critical Dates for SEMI Standards Ballots

Cycle	Ballot Submission Date	Voting Period Starts	Voting Period ends
Cycle 1	January 4	January 12	February 12
Cycle 2	February 2	February 16	March 17
Cycle 3	March 1	March 14	April 13
Cycle 4	April 15	April 26	May 26
Cycle 5	May 10	May 24	June 23
Cycle 6	July 22	August 1	September 1
Cycle 7	August 17	August 31	September 30
Cycle 8	October 17	October 24	November 23
Cycle 9	November 16	November 30	December 30

A&R Ballot Review

A&R Cycle	Result	Notes
May 2016	 A&R_201605	<p>Doc. 5944 (NA LC) and Doc. 5970-LI1 (NA EHS) failed.</p> <ul style="list-style-type: none"> ✓ 5944 (Revision to F63): Editorial Changesは委員会で何をどのように変更するか明示しなければならないが、SEMI Staffにより処理されるとレポートに記載されており、その具体的内容がきちんと書かれていない。 (PM. 2.11.4 違反) ✓ 5970 (Revision to S14), LI-1 (Changes to Terminology to Align with SEMI S10): S14のタイトルの一部“Safety Guidelines” → “Safety Guideline”の変更をバロットにかけず、バロットレビュー時にEditorial Changeで処理 (PM. Appendix 4違反)
July 2016	 A&R_201607	All passed. However, publication of Doc. 5601A (New Standard: Specification for Wafer Job Management) is on hold since it received a Minority Report (MR).
August 2016	 A&R_201608	<p>Doc. 5970-LI1 (NA EHS) Failed.</p> <ul style="list-style-type: none"> ✓ 5970 (Revision to S14), LI-1 (Changes to Terminology to Align with SEMI S10): ★経緯が複雑なので次のスライドでご確認ください

Doc. 5970-LI1 (NA EHS) がA&Rで否認された経緯

- 2016年5月A&R:否認
 - 理由:
 - S14のタイトルの一部“Safety Guidelines” から“Safety Guideline”の変更をバロットにかけず、バロットレビュー時にEditorial Changeで処理 (PM. Appendix 4違反)
- 2016年7月 (SEMICON West 2016) NA EHS TC Chapter Meeting:
 - TC Chapter会議で前回会議でのEditorial Changeを取り消す決議 (Re-adjudication)を行い、Non-Conforming Title状態の5970をそのまま承認してA&Rに送った
- 2016年8月A&R:否認
 - Re-adjudicationが正当化されるかどうかを中心に議論、以下の理由で否認
 - Regs/PMには「Re-adjudicationは禁止」という文言はないものの、AdjudicationをBackground Statementに示された日に行うことを義務付ける規定している。
 - Robert Rules of Order中のReconsider (Motionの再審議)は会議当日中にしか適用できないと規定している。
 - 同じく、Robert Rules of Order中のRescind (議決内容の再審議)に関しても、議決に基づきAction (今回の場合はA&R審議・否決etc)が起こされ、それをそのActionが取り消し不可能な場合には適用できないと規定している。

SEMI Standards Publications

Publication Cycle	New	Revised	Reapproved	Withdrawn
January 2016	6	7	0	0
February 2016	4	4	3	0
March 2016	2	21	4	0
April 2016	0	8	10	0
May 2016	2	3	0	0
June 2016	0	4	3	0
July 2016	0	2	0	0
August 2016	0	7	3	0
September 2016	0	1	0	0

- Total SEMI Standards in portfolio: 964
 - Includes 152 Inactive Standards

A&R Ballot Review

- FPD – August 2016
 - FPD Materials & Components Japan Chapter
 - 6010, Reapproval of SEMI D34-0710, Test Method for FPD Polarizing Films - *Passed*
 - 6011, Reapproval of SEMI D38-0211, Guide for Quality Area of LCD Masks – *Passed*
 - 6012 Reapproval of SEMI D39-0704 (Reapproved 0710), Specification for Markers on FPD Polarizing – *Passed*
 - 6013 Reapproval of SEMI D6-0211, Specification for Liquid Crystal Display (LCD) Mask Substrates - *Passed*

PPT Template Update

- SEMI PPT template is updated again.
-



SEMI Std
Template 短縮版

JRSC Topics

- プランニング会議
 - 8月26日(金)13:30－16:30 開催済み
 - SEMIジャパン会議室
 - テーマ:「先端技術と標準」
 - ※プランニング会議に先立ち午前中にスタンダードメンバートレーニング(入門編)を開催

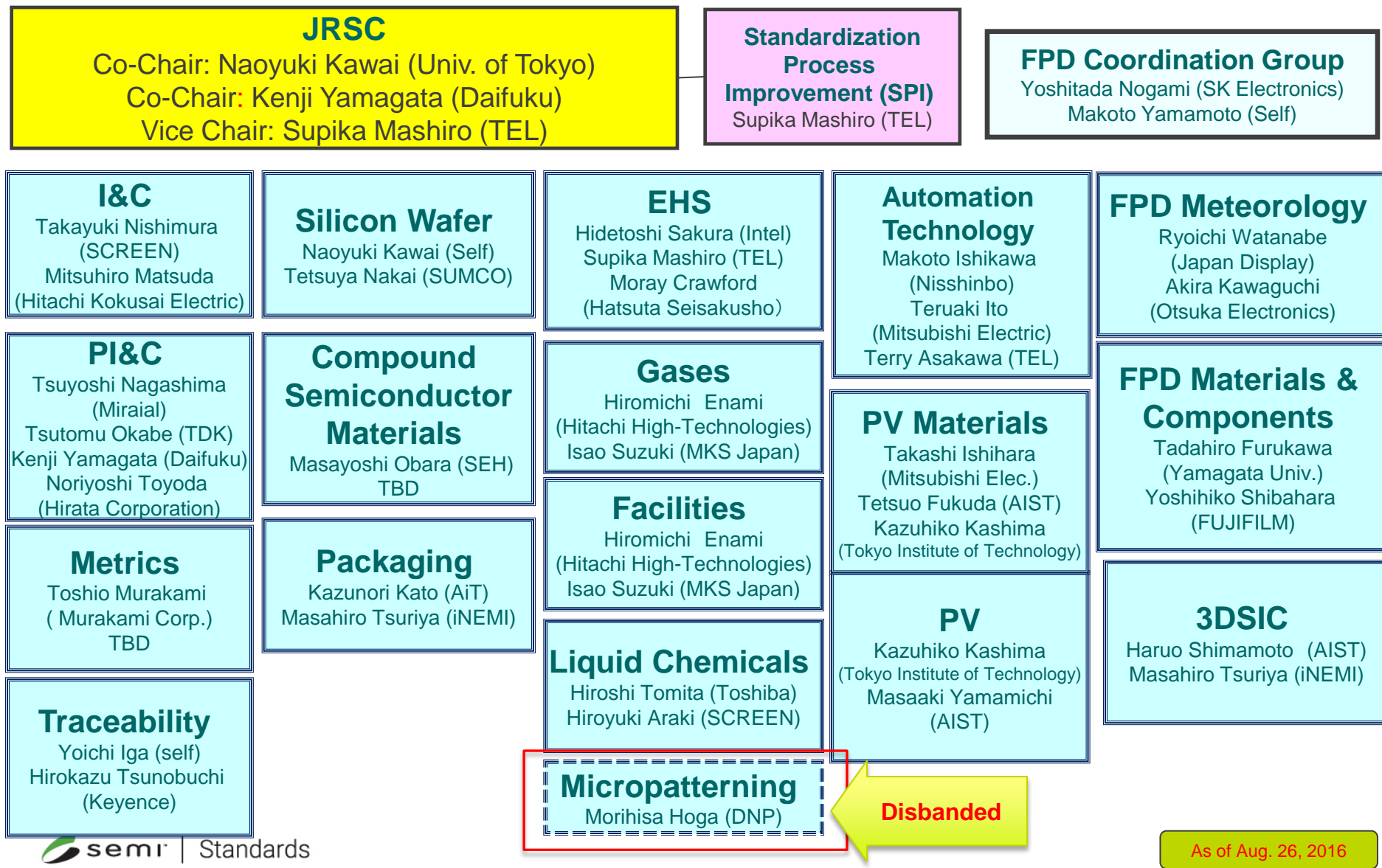


2016_JRSC
ng Meeting 2016

JRSC Topics

- Japan Micropatterning TC Chapter has been disbanded
- JRSC Membership Change
 - Noriyoshi Toyoda (Hirata Corporation) appointed as PI&C Japan TC Chapter Chair
 - Morihisa Houga (DNP) stepped down from the chair position due to disbandment of Micropatterning Japan TC Chapter
 - Hiromu Takatsuka (PVTEC) stepped down from the chair position of PV Japan TC Chapter

JRSC Organization Chart



SEMI通信

- 2015_04_ノッチレス・ウェーハ スタANDARD成立
- 2015_05_太陽電池モジュールの欠陥とレーザースキャニングのSTANDARD開発
- 2015_06_SEMIにおける3D-IC標準化動向
- 2015_07_STEP:S2の過去10年を振り返って(STEP:S2と私)
- 2015_08_SEMI安全ガイドライン出版-3年に一度の改訂
- 2015_09_Live Gas Study Groupの活動報告
- 2015_10_JEITA規格のSEMI規格への移行について
- 2015_11_SEMI FlowMaster (フロー・ショップ型製造ライン構築支援コンセプト)
- 2015_12_3DS-IC日本地区技術委員会の活動
- 2016_02_SEMI E170 (セキュリティ強化されたレシピ管理システム用基盤STANDARD)
- 2016_03_フラットパネルディスプレイ(FPD)の標準化、その歩みと今後へ向けての取り組み
- 2016_04_薄チップを安全に搬送する「粘着トレイ」の新規SEMISTANDARD化
- 2016_05_EISS TFでアクセス・コントロールの標準仕様化検討を開始
- 2016_06_酢酸蒸気暴露によるPVセルの試験方法
- 2016_08_SEMISTANDARDとスマート・マニファクチャリング
- 2016_09_CMPスラリーの密度測定方法
- 2016_10_「送電網(パワーグリッド)高調波の互換性」に関する新STANDARDの開発 (予定)

Staff Update

- China
 - Sophia Huang
 - China HB-LED
 - China Photovoltaic
- EU
 - James Amano and Kevin Nguyen
 - All EU TC Chapters
- Japan, Korea , Taiwan
 - No update
- North America
 - Inna Skvortsova
 - Automated Test Equipment
 - Information & Control
 - Liquid Chemicals
 - Metrics
 - Traceability
 - Laura Nguyen
 - 3DS-IC
 - HB-LED
 - Facilities
 - Gases
 - MEMS / NEMS
 - Physical Interfaces & Carriers
 - PV Materials
 - Kevin Nguyen
 - EHS
 - Micropatterning
 - Silicon Wafer

Staff Contact Information from Jan. 1, 2016

Committee	Staff
Gases, Facilities, FPD M&C, FPD Meteorology, Liquid Chemical SIG: SEA, CGMG	<i>Naoko Tejima</i> <i>Manager, Standards & EHS</i> ntejima@semi.org
PI&C, I&C, Metrics, Traceability, PV, PV Materials, Assembly & Packaging, 3DS-IC	<i>Chie Yanagisawa</i> <i>Manager, Standards & EHS</i> cyanagisawa@semi.org
JRSC, SPI TF, Compound, Micropatterning, Silicon Wafer, EHS, Automation Technology, Test, EHS SIG: ESG, SMG, EHS	<i>Junko Collins</i> <i>Director, Standards & EHS</i> jcollins@semi.org
Others	Staff
Standards Products General Information, SEMIViews	<i>C. Yanagisawa</i>
Other Standards Operation	<i>J. Collins</i>

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Thank you

Backup

Doc. 5970-LI1 (NA EHS) がA&Rで否認された経緯（原文）

- ① もともと5970はNon-conforming Titleであることを指摘するComment (Larryから)を受け取っていたのですが、NA EH&S TC ChapterはLarryからのRecommendation「次の利用可能サイクルでProcedure Manual Appendix 4にしたがってタイトル修正をかけること」と言うのを無視し、Editorial Changeを使ってNon-conforming Titleを修正して委員会審議を通過しA&Rに送られました。(4月)
- ② A&Rは5970を手続き違反(Procedure Manual Appendix 4)として否認しました(5月)
- ③ NA EH&S NA EH&S TC ChapterはSEMICON West時のTC Chapter会議で前回会議でのEditorial ChangeをUndoする決議(Re-adjudication)を行い、Non-Conforming Title状態の5970をそのまま承認してA&Rに送りました(7月)
- ④ A&RではRe-adjudicationが正当化されるかどうかを中心に議論されました。結局(i)Regs/PMには「Re-adjudicationは禁止」という文言はないものの、AdjudicationをBackground Statementに示された日に行うことを義務付ける規定と、(ii)Robert Rules of OrderのなかのReconsider (Motionの再審議)は会議当日中にしか適用できず、(iii)同じくRobert Rules of OrderのなかのRescind (議決内容の再審議)に関しても議決に基づきAction (今回の場合はA&R審議・否決etc)が起こされそれをそのActionが取り消し不可能な場合には適用できない。という理由で再びA&Rでは否認されています。(8月)